

## AES and TDS Study of the Adsorption of NH<sub>3</sub> and NO On V<sub>2</sub>O<sub>5</sub> and TiO<sub>2</sub> Surfaces: Mechanistic Implications

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The adsorption of NH<sub>3</sub> and NO on pure V<sub>2</sub>O<sub>5</sub> and on TiO<sub>2</sub> samples at pressures (ca. 25 Torr) and temperatures (room temperature to 675 K) close to those used in industry with V<sub>2</sub>O<sub>5</sub>/TiO<sub>2</sub> catalysts to carry out the NO reduction with NH<sub>3</sub> has been studied by Auger electron spectroscopy (AES) and thermal desorption spectroscopy (TDS), using a UHV chamber equipped with a built-in high pressure cell (up to 1 atm). NH<sub>3</sub> adsorption takes place over the whole range of temperatures studied on TiO<sub>2</sub> and on V<sub>2</sub>O<sub>5</sub> as well as on reduced V<sub>2</sub>O<sub>5</sub> surfaces. NO adsorption occurs only on TiO<sub>2</sub> and on reduced V<sub>2</sub>O<sub>5</sub> but not on oxidized V<sub>2</sub>O<sub>5</sub> surfaces. It is shown that NH<sub>3</sub> reduces the vanadium pentoxide surface resulting in the production of N<sub>2</sub>O. The presence of N<sub>2</sub>O, NO, and O<sub>2</sub> results in the reoxidation of the vanadium surface with the nitrogen oxides being converted into N<sub>2</sub>. No evidence for the NO + NH<sub>3</sub> reaction has been obtained on the TiO<sub>2</sub> surface. However, NO adsorption on TiO<sub>2</sub> appears to be a main factor for the catalyst effectiveness in V<sub>2</sub>O<sub>5</sub>/TiO<sub>2</sub> samples since it may provide a source of NO at the interface of vanadia islands on TiO<sub>2</sub> in the actual catalyst. Finally, from TDS and AES data a reaction mechanism is suggested that may explain the reduction of NO to N<sub>2</sub> as well as the side reaction responsible for the production of N<sub>2</sub>O. © 1989 Academic Press, Inc.

### INTRODUCTION

Interest in air quality and emission control has resulted in considerable research dealing with the selective reduction of nitrogen oxides. An extensive review of this subject has recently been published (1). Among the catalysts tested, vanadium oxides supported on TiO<sub>2</sub> seem to be preferred for catalyzing the NO<sub>x</sub> + NH<sub>3</sub> + O<sub>2</sub> reaction. Although NO<sub>x</sub> can be reduced to N<sub>2</sub> with the use of reducing gases such as CH<sub>4</sub>, H<sub>2</sub>, and CO, ammonia is preferred since the other gases are readily consumed by reaction with O<sub>2</sub>. The characterization of the supported vanadium species by different techniques, such as extended X-ray absorption fine structure (EXAFS) (2, 3),

high resolution electron microscopy (HREM) (4), X-ray photoelectron spectroscopy (XPS) (5-8, 34), laser Raman spectroscopy (9, 10), and electron spin resonance (ESR) (11, 13), has been reported. Kinetic studies directed toward the elucidation of the reaction mechanism (14, 27), in some cases supported by theoretical approaches (28), have been undertaken and the preparation of titania-supported V<sub>2</sub>O<sub>5</sub> with improved redox properties (29) has been described.

Although surface sensitive electron spectroscopies are excellent tools for studying the catalyst surfaces, little has been reported on the use of surface science techniques for studying the adsorption of NH<sub>3</sub> and NO on V<sub>2</sub>O<sub>5</sub> and on V<sub>2</sub>O<sub>5</sub>/TiO<sub>2</sub> surfaces. Only Tsai *et al.* (30, 31) have reported an AES study of the surface of supported Group VIII metals for the NH<sub>3</sub> + NO reaction after SO<sub>2</sub> poisoning. Most pa-

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pers assume that reduction of supported  $V_2O_5$  occurs during the  $NO + NH_3$  reaction, but the mechanism through which the reduction takes place has not been verified.

The aim of the present work was to study the adsorption of  $NO$  and  $NH_3$  on pure  $V_2O_5$  and on  $TiO_2$  by means of Auger electron spectroscopy (AES) and thermal desorption spectroscopy (TDS). On the basis of our findings, elementary steps are proposed for the  $NO + NH_3 + O_2$  reaction on  $V_2O_5$  and  $V_2O_5/TiO_2$ . As will be shown later,  $NO$  cannot adsorb on fully oxidized  $V_2O_5$  surfaces. The experimental techniques utilized in this work allowed us to demonstrate the reduction of the vanadium oxide catalyst in the presence of  $NH_3$ , which in turn is oxidized to  $N_2O$ . In addition, the role of oxygen in the reactant mixture has been established mainly as a participant in the  $NO$  and  $NH_3$  competition for the reduced surface sites improving the catalytic life.

#### EXPERIMENTAL

In this study a powdered vanadium oxide catalysts ( $V_2O_5$ ) from Aldrich Chemical Co. (99.999% pure) was employed. High purity gases,  $NH_3$ ,  $NO$ , and  $O_2$ , were obtained from Matheson and used without further purification. Pure  $TiO_2$  (99%) as anatase was supplied by Südchemie.

The apparatus used for the AES and TDS studies has been previously described (32). It consists of a stainless-steel bell jar, evacuated to pressures below  $5 \times 10^{-9}$  Torr by a Varian VHS6 diffusion pump, backed by a rotary pump. A built-in high pressure cell isolates the sample from the UHV environment accounting for sample treatments under different atmospheres up to 1 atm (32).

The sample holder is part of the high pressure cell. When it is open, the cell exposes the sample to ultrahigh vacuum (UHV) for AES and/or TDS analysis, and when it is closed, it becomes a part of the reactor used for sample treatments. The sample is pressed against a gold coated stainless-steel grid, and it is in intimate con-

tact with a chromel-alumel thermocouple. The grid is held against a gold foil by two lateral flaps. By passing current through the foil, the sample can be heated to the desired temperature.

The Auger electrons were detected by a double-pass cylindrical mirror analyzer (CMA) equipped with a coaxial electron gun (Physical electronics 15-255G). A 6 eV peak-to-peak modulation and a response time of 20 ms were selected. The electron gun was always operated at 1 kV and 0.8 mA at normal incidence.

For TDS studies, the adsorbate was introduced into the high pressure cell at pressures close to those usually achieved under actual industrial conditions (ca. 25 Torr), allowing it to circulate at the temperature chosen (room temperature to 675 K) for 15 min. After that, the sample was cooled in the adsorbate atmosphere and outgassed in the UHV chamber, at the adsorption temperature, until the system base pressure was achieved. The sample was then heated under UHV conditions at a constant heating rate ( $15 \text{ K s}^{-1}$ ). A mass spectrometer (UTI 100C) monitored the gas evolution of a given mass, and a plot of the signal intensity versus temperature was generated on an XY recorder (Hewlett-Packard 7044B). Alternatively, the sample was exposed to the reactant gases in a UHV environment in which case the gases were introduced into the UHV chamber through a leak valve at pressures below  $1.10^{-6}$  Torr.

#### RESULTS

##### (i) Studies on $V_2O_5$

The adsorption of  $NH_3$  and  $NO$  on  $V_2O_5$  has been studied by AES and TDS. The presence of carbon contamination on  $V_2O_5$  has been described as responsible for the reactivity of thin films of  $V_2O_5$  on gold foils (33). The formation of  $CO$  and/or  $CO_2$  that desorbs at ca. 675 K might be responsible for the generation of oxygen vacancies on the  $V_2O_5$  surface leaving exposed  $V^{4+}$  species that can then react with the adsorbates

(3, 33). To avoid any interference from coadsorbed species we carried out an oxidation treatment that would leave a clean V<sub>2</sub>O<sub>5</sub> surface, before adsorbing NH<sub>3</sub> and/or NO. Figure 1 shows the AES spectrum of the vanadia sample after oxidizing it under 40 Torr of O<sub>2</sub> at 675 K for 15 min followed by heating at the same temperature for 10 min in the UHV chamber; this results in a clean V<sub>2</sub>O<sub>5</sub> sample characterized by the presence of the V(L<sub>3</sub>M<sub>23</sub>M<sub>23</sub>) and V(L<sub>3</sub>M<sub>23</sub>M<sub>45</sub>) transitions at 430 and 469 eV, respectively, and at 510 eV for the O(KLL) transition.

Unfortunately the oxidation state of the vanadium species is not unequivocally obtainable by AES. Even at low peak-to-peak modulation (2 eV), the intensity ratio between the O(KLL) and V(L<sub>3</sub>M<sub>23</sub>M<sub>23</sub>) lines is the same, 2.4, for the oxidized and reduced vanadia samples. Various authors (33, 35–37) have drawn conclusions from the relative intensity of the lines but they used oxidized vanadia films. In our study bulk vanadia was used and to observe a change in the AES spectrum, much of the sample would have had to be reduced rather than just the surface.

Both the adsorption of NH<sub>3</sub> and of NO have been carried out as a function of temperature. Figure 2, curve A, displays the

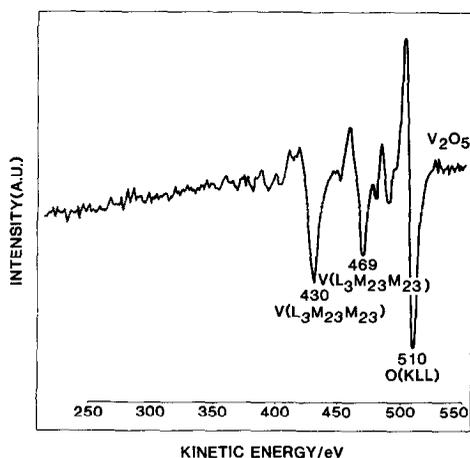


FIG. 1. AES spectrum of a clean oxidized V<sub>2</sub>O<sub>5</sub> sample. Peak-to-peak modulation 2 eV.

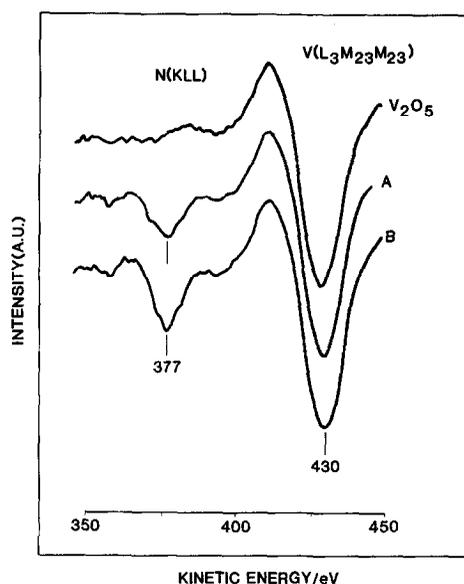


FIG. 2. AES spectra for the adsorption of NH<sub>3</sub> at RT (A) on a clean oxidized V<sub>2</sub>O<sub>5</sub> sample, (B) on a NH<sub>3</sub>-reduced V<sub>2</sub>O<sub>5</sub> sample, compared to the AES spectrum for clean oxidized V<sub>2</sub>O<sub>5</sub> (Fig. 1).

AES spectrum of V<sub>2</sub>O<sub>5</sub> after adsorption of 25 Torr of NH<sub>3</sub> at room temperature. The presence of a new peak at 377 eV, with respect to the pure V<sub>2</sub>O<sub>5</sub> spectrum, is now noticeable; this peak can be assigned to the N(KLL) transition indicating that NH<sub>3</sub> can be adsorbed at room temperature. After heating of the sample to 775 K the nitrogen peak disappears. On this presumably reduced vanadium surface, the adsorption of NH<sub>3</sub> also occurs (Fig. 2 curve B). No conclusions can be drawn about the nature of the resulting ammonia species on the basis of the AES spectrum.

Evidence for the reduction of the V<sub>2</sub>O<sub>5</sub> surface can be obtained from TDS experiments. One of the possible mechanisms for the NH<sub>3</sub> + NO reaction includes a redox process, which implies the oxidation of NH<sub>3</sub> to N<sub>2</sub>O using oxygen from the V<sub>2</sub>O<sub>5</sub> lattice. To test the possibility of such a mechanism several experiments were performed in which, after adsorbing 25 Torr of NH<sub>3</sub> at room temperature, amu's 44 (N<sub>2</sub>O<sup>+</sup>) and 30 (NO<sup>+</sup>) were monitored and the signal corresponding to amu 15 (NH<sup>+</sup>) was an-

alyzed as well. In both cases, similar TDS profiles were obtained showing peaks at 643 K (Fig. 3), indicating that  $V_2O_5$  is reduced by  $NH_3$  which in turn is oxidized to  $N_2O$ .

The adsorption of  $NH_3$  on  $V_2O_5$  has also been studied at 575 and 675 K. AES spectra of the interaction under 25 Torr of  $NH_3$  at 575 and 675 K are shown in Fig. 4; the experimental procedure was as follows: after oxidizing the  $V_2O_5$  sample, 25 Torr of  $NH_3$  was introduced in the high pressure cell, heated to the reaction temperature for 15 min, and then cooled to room temperature in such an atmosphere and outgassed in the UHV chamber until the chamber base pressure was reached. After this treatment a nitrogen peak appears in the AES spectrum that cannot be eliminated by heating at the reaction temperature in UHV, as shown in Fig. 4; only by heating at 775 K under vacuum does the nitrogen peak disappear. However, this nitrogen peak, which cannot be eliminated by heating in UHV at the reaction temperatures, readily disappears by heating in  $O_2$  at 675 K.

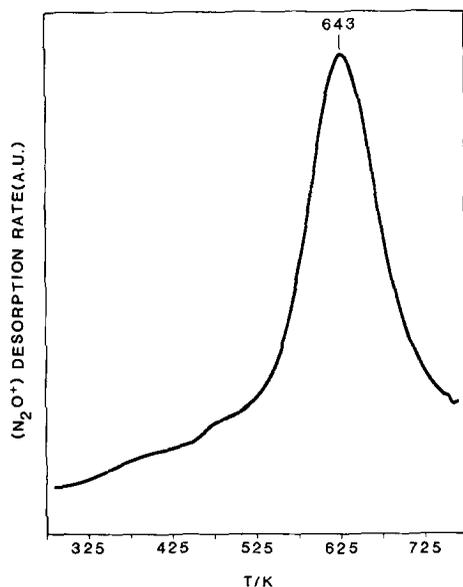


FIG. 3. TDS spectrum for the desorption of  $N_2O$  after adsorbing 25 Torr of  $NH_3$  at RT on a clean oxidized  $V_2O_5$  sample.

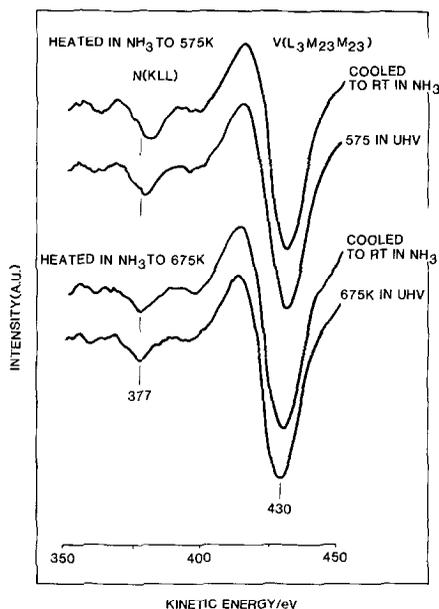


FIG. 4. AES spectra for the adsorption of  $NH_3$  on a clean oxidized  $V_2O_5$  samples at 575 and 675 K.

Figure 5 shows a plot of the TDS profile for the desorption of  $NH_3$  from the  $V_2O_5$  sample previously heated to 675 K under 25 Torr of  $NH_3$ . One peak is obtained, giving the same desorption energy as that obtained after ammonia adsorption at room

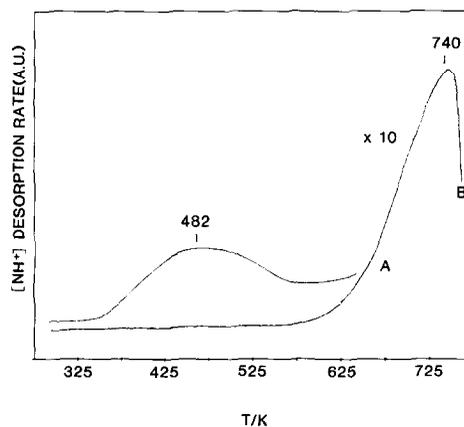


FIG. 5. TDS spectra for the desorption of  $NH_3$  after adsorbing 25 Torr of  $NH_3$  at 675 K. First run: the sample was heated to 675 K and cooled in UHV (A). Second run: heated to 775 K in UHV after the first run (B).

temperature. Since after the heat treatment in ammonia the sample is cooled down in an ammonia atmosphere, this peak may correspond to the adsorption of NH<sub>3</sub> at room temperature. However, after heating under vacuum at 675 K for 10 min the nitrogen peak remains in the AES spectrum, as shown in Fig. 4. After heating to 775 K a new TDS peak appears at 740 K, as shown in Fig. 5. On the basis of TDS and AES experiments, the identification of this peak remains uncertain. However, XPS and ESR spectra of V<sub>2</sub>O<sub>5</sub>/TiO<sub>2</sub> samples after treatment with NH<sub>3</sub> at reaction temperatures showed additional evidence for the dissociation of NH<sub>3</sub> (38). After reaction with ammonia, the V<sub>2</sub>O<sub>5</sub> sample showed a sharp signal in the ESR spectrum that may be ascribed to electrons trapped in oxygen vacancies; at the same time a N(1s) signal at 399.6 eV can be observed in the XPS spectrum; this binding energy is 1.3 eV lower than that reported for NH<sub>4</sub>VO<sub>3</sub> or NH<sub>4</sub><sup>+</sup> adsorbed on V<sub>2</sub>O<sub>5</sub> (15) suggesting the

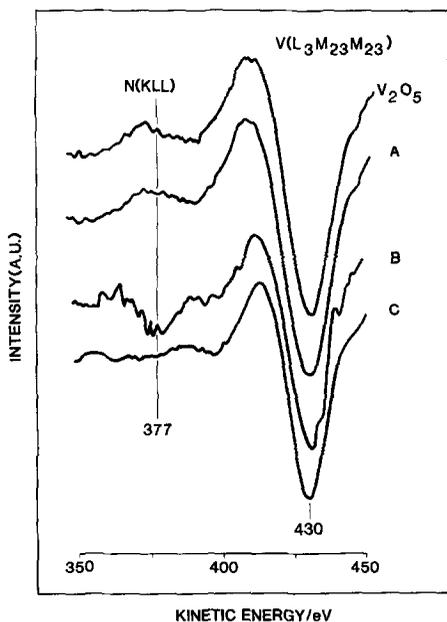


FIG. 6. AES spectrum of clean oxidized V<sub>2</sub>O<sub>5</sub> compared to AES spectra for the adsorption of NO at RT (A) on a clean oxidized V<sub>2</sub>O<sub>5</sub> sample, (B) on a NH<sub>3</sub>-reduced V<sub>2</sub>O<sub>5</sub> sample heated in UHV to 775 K, and (C) after heating (B) to 775 K in UHV.

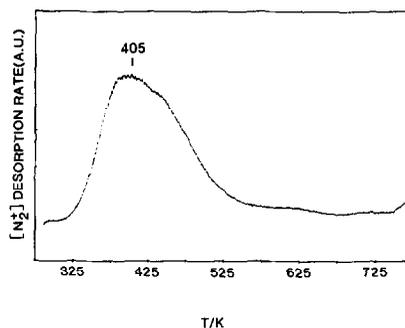


FIG. 7. TDS spectrum for the desorption of N<sub>2</sub> after adsorbing 25 Torr of NO at RT on a NH<sub>3</sub>-reduced V<sub>2</sub>O<sub>5</sub> sample.

dissociation proposed. The observed value (399.6 eV) is close to that reported by Au and Roberts (39) for NH<sub>2</sub> species adsorbed on clean and oxidized Mg(0001) crystals (399.0 eV) in the presence of O<sub>2</sub>. However, although reporting the amide species, they do not characterize the bonding of the NH<sub>2</sub> species to the Mg(0001) surface.

NO was not adsorbed on a clean oxidized V<sub>2</sub>O<sub>5</sub> surface under our experimental conditions; NO could also not be adsorbed on V<sub>2</sub>O<sub>5</sub> that was covered with a monolayer of preadsorbed NH<sub>3</sub> (Fig. 6). NO adsorption at room temperature was observed on a V<sub>2</sub>O<sub>5</sub> sample previously reduced with ammonia and outgassed in UHV at 775 K (Fig. 6). Heating the sample after NO adsorption to 775 K, the adsorbed species disappears. This result indicates that NO can interact with the reduced vanadium sites. In Fig. 7 the TDS (following amu 28 (N<sub>2</sub><sup>+</sup>)) of that adsorbed species is shown. A peak centered at 405 K is observed which indicates that at reaction temperatures the NO can reoxidize the reduced vanadium sites while being reduced to N<sub>2</sub>.

In a semiquantitative approach the N/V peak-to-peak ratio has been obtained from the AES spectra plotted in Figs. 2, 3, and 6 (Table 1). From this ratio it is possible to state that at least two different nitrogenated species are held by the V<sub>2</sub>O<sub>5</sub> surface in adsorbing NH<sub>3</sub>: the first has its maximum desorption rate at temperatures between

TABLE I  
N/V Peak-to-Peak Ratio

Adsorbate	Treatment	Temperature (K)	N/V
NH <sub>3</sub>	Oxidized	300	0.21
NH <sub>3</sub>	NH <sub>3</sub> -reduced	300	0.29
NH <sub>3</sub>	Cooled to RT in NH <sub>3</sub>	575	0.18
NH <sub>3</sub>	Heated to 575 K in UHV	575	0.15
NH <sub>3</sub>	Cooled to RT in NH <sub>3</sub>	675	0.12
NH <sub>3</sub>	Heated to 675 K in UHV	675	0.13
NO	Oxidized	300	0.00
NO	Reduced	300	0.22

room temperature and 575 K while the second has its maximum desorption rate between 575 and 775 K; this is in agreement with the TDS results (Fig. 5). Surprisingly, after reaction in NH<sub>3</sub> at 575 or 675 K the vanadia surface undergoes modifications that prevent any further NH<sub>3</sub> adsorption at room temperature. If we compare the N/V ratio for NH<sub>3</sub> adsorption at room temperature (0.21) with the value obtained after reaction at 675 K and further cooling to room temperature (0.12) we must assume modification of the surface relative to the original one. This surface modification of the clean oxidized V<sub>2</sub>O<sub>5</sub> surface cannot be ascribed to its reduction since the reduced surface adsorbs even more NH<sub>3</sub> than the oxidized one, Table I. Since the reaction proceeds in a closed system, the reaction products are present in the high pressure cell; these products, as demonstrated by TDS (Fig. 3) are N<sub>2</sub>O and H<sub>2</sub>O; assuming, according to Miyamoto *et al.* (12, 18), that N<sub>2</sub>O may react with the reduced sites reoxidizing them, then only NH<sub>3</sub>, N<sub>2</sub>, and H<sub>2</sub>O should be present in the reactor and the presence of water should be responsible for the difference observed in Table I. From this result it is possible to deduce either that H<sub>2</sub>O adsorption on the V<sub>2</sub>O<sub>5</sub> surface prevents any further ammonia adsorption or that the in-

teraction of the NH<sub>3</sub> molecules with the hydroxylated surface is so weak that NH<sub>3</sub> desorption takes place at room temperature in a UHV environment.

Furthermore, the N/V peak-to-peak ratio for NO adsorption at room temperature is similar to that obtained for ammonia adsorption (Table I). This indicates that the number of adsorbed NO species is equal to the number of NH<sub>3</sub>-adsorbed species, pointing to a NO to NH<sub>3</sub> ratio equal to one in the NO + NH<sub>3</sub> reaction.

#### (ii) Studies on TiO<sub>2</sub>

The adsorption of NO on TiO<sub>2</sub> has been studied by TDS as a function of temperature. The shape of the TDS spectra is the same regardless of the adsorption temperature and is characterized by a peak centered at 385 K. Neither N<sub>2</sub> nor N<sub>2</sub>O was observed, indicating that NO adsorbs molecularly on the TiO<sub>2</sub> surface (Fig. 8). However, the amount adsorbed decreases when the reaction temperature increases. If successive 18 L (1 Langmuir = 10<sup>-6</sup> Torr ×

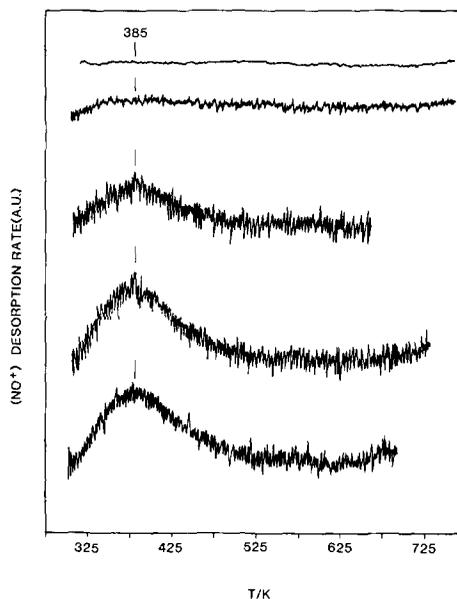


FIG. 8. TDS spectra for the desorption of NO after adsorbing successive 18-L doses of NO to an oxidized TiO<sub>2</sub> surface. The bottom profile corresponds to the first dose.

sec) doses of NO are provided to the TiO<sub>2</sub> surface, the amount adsorbed decreases to a level in which no more NO can be adsorbed, indicating a poisoning of the TiO<sub>2</sub> surface by NO species. When the adsorption is carried out in the high pressure cell under 25 Torr of NO, a single broad peak is observed in the TDS. This peak has higher desorption energy, the maximum appearing at 468 K.

NH<sub>3</sub> adsorption also takes place on TiO<sub>2</sub> (Fig. 9). The TDS spectrum of ammonia is characterized by a single broad peak which is centered at 445 K after 5 L adsorption at RT. The temperature corresponding to the maximum in the TDS peak shifts to higher values when increasing the NH<sub>3</sub> dose, indicating either a dependence of the binding energy on coverage or a population of different TiO<sub>2</sub> sites. On adsorbing NH<sub>3</sub> at either 373 or 473 K, a decrease in the amount adsorbed is observed as well as a shift to higher desorption temperatures (Fig. 9). When the NH<sub>3</sub> adsorption is at 373 K, an NH<sub>3</sub> desorption peak in the TDS profile at 495 K results; this peak position is independent of the NH<sub>3</sub> dose, pointing to the existence of different adsorption sites on the TiO<sub>2</sub> surface. The TDS after NH<sub>3</sub> adsorption at 473 K results in a hardly noticeable peak at about 600 K, indicating that at this temperature almost all the active surface sites on the TiO<sub>2</sub> surface have been removed.

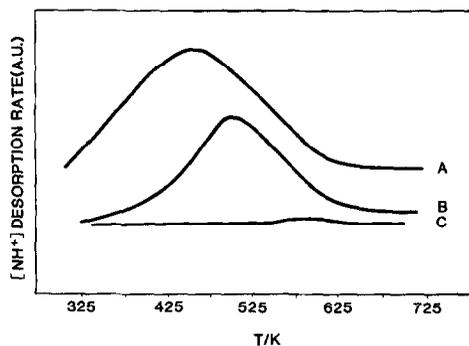


FIG. 9. TDS spectra for the desorption of NH<sub>3</sub>. (A) 5 L at RT; (B) 5 L at 375 K; (C) 5 L at 475 K.

This points to an interaction between the ammonia molecule with the TiO<sub>2</sub> surface through weakly bound hydroxyl groups that are easily removed by heating at mild temperatures.

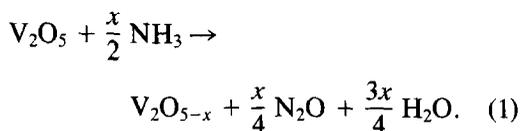
The reaction of NO and NH<sub>3</sub> on the TiO<sub>2</sub> surface has also been studied by leaking a NO + NH<sub>3</sub> (2:3 ratio) mixture into the UHV chamber at doses up to 20 L. This experiment showed that neither N<sub>2</sub> nor N<sub>2</sub>O are desorbed from the TiO<sub>2</sub> surface in the temperature range 300–700 K and that, therefore, there is no reduction of NO by NH<sub>3</sub> occurring on TiO<sub>2</sub> in this temperature range.

#### DISCUSSION

Although the NH<sub>3</sub> + NO reaction has been the subject of numerous investigations (1), the nature of the active sites and of the reaction mechanism is still undetermined. The results described above provide some information on the role of the support and on the active phase of V<sub>2</sub>O<sub>5</sub>/TiO<sub>2</sub> catalysts for the removal of nitrogen oxides in stack and power gas exhaust systems.

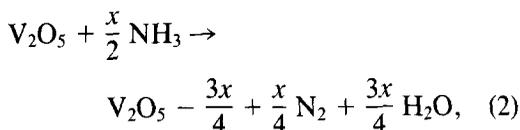
The reduction of V<sub>2</sub>O<sub>5</sub> in the presence of NH<sub>3</sub>, either as a bulk oxide or when supported, is generally proposed in the literature (18, 27).

Our results clearly indicate that the surface of the V<sub>2</sub>O<sub>5</sub> catalyst is reduced in the presence of NH<sub>3</sub> and in the absence of NO, leaving behind a surface vacancy according to the following scheme:



The reduction of the V<sub>2</sub>O<sub>5</sub> surface and the subsequent oxidation of the NH<sub>3</sub> molecule to N<sub>2</sub>O has been demonstrated by TDS (Fig. 4). This result appears to contradict the NH<sub>3</sub> – NO adduct proposed by Miyamoto (18, 28) and agrees with the

scheme proposed by Bosch *et al.* (23),

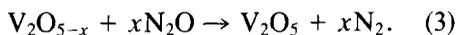


in which case the oxygen defect may be present as a surface vacancy or a surface hydroxyl group.

Our results do not exclude the possible presence of hydroxyl groups or surface vacancies. However, the presence of a surface vacancy or a hydroxyl group should depend on the temperature at which the reaction is carried out. Dehydroxylation of  $\text{V}_2\text{O}_5$  and  $\text{V}_2\text{O}_5/\text{TiO}_2$  at temperatures below 550 K has been mentioned in the literature (13, 40). The reduction of the vanadium site by dehydroxylation has also been pointed out by Busca *et al.* (13).

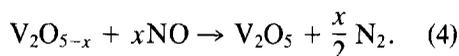
Although it has been shown that the presence of water in the reactant mixture does not affect the temperature at which the maximum NO conversion occurs (41), it will be shown later in this article that surface hydroxylation is an important factor in the role of  $\text{O}_2$  species during the reaction.

A difference between the stoichiometric scheme proposed by Bosch *et al.* (23) and that proposed here is the presence of  $\text{N}_2\text{O}$  instead of  $\text{N}_2$ . Thermodynamically, the  $\text{N}_2\text{O}$  species is stable with respect to its decomposition into  $\text{N}_2$  and  $\text{O}_2$  at the reaction temperatures (575–675 K) and the stability increases with increasing temperature. Thus, the presence of  $\text{N}_2$  instead of  $\text{N}_2\text{O}$  in the reaction products, as postulated in (23), must be due to a further interaction of  $\text{N}_2\text{O}$  with surface vacancies:



Thus the surface is reoxidized to  $\text{V}^{5+}$ , while the  $\text{N}_2\text{O}$  in turn is reduced to  $\text{N}_2$ . In fact, by combining Eqs. (1) and (3) the scheme proposed by Bosch *et al.* (23), Eq. (2), is obtained. A reduction of  $\text{N}_2\text{O}$  with  $\text{NH}_3$  to produce  $\text{N}_2$  and  $\text{H}_2\text{O}$  which occurs on metals is not likely to occur on oxides.

The desorption of  $\text{N}_2\text{O}$  at reaction temperatures, leaving behind a reduced site, raises the question of which species is able to reoxidize such vanadium sites. Since the adsorption of NO on the reduced sites is possible (Fig. 6) and results in NO being reduced to  $\text{N}_2$  at reaction temperatures (Fig. 7), the following elementary step can also be proposed:

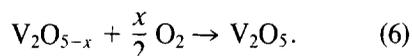


By combining Eqs. (1), (3), and (4) the overall reaction can be described as

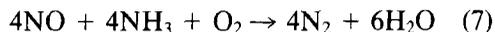


This stoichiometry, proposed by Nam *et al.* (26) for the  $\text{NH}_3 + \text{NO}$  reaction on  $\text{V}_2\text{O}_5/\text{TiO}_2$  catalysts, cannot account for the drop in NO conversion in the absence of  $\text{O}_2$  reported in the literature (11, 23, 25, 41).

Taking into account the presence of  $\text{O}_2$  in the reaction mixture, the following step can also be hypothesized:



The overall reaction may then be written



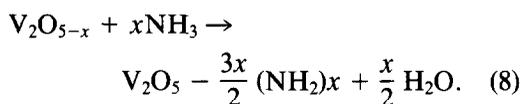
which is in good agreement with the stoichiometries proposed in the literature (43, 44). This stoichiometry also fits the NO and  $\text{NH}_3$  coverages obtained by AES on  $\text{V}_2\text{O}_5$  (Table 1).

The kinetics of the  $\text{NH}_3 + \text{NO}$  reaction has been extensively studied (14, 27). While some disagreement appears in the literature data (11, 16, 17, 19–26, 45), the kinetic results may be summarized in an oversimplified manner: a positive order in NO and a zero or even slightly negative order in  $\text{NH}_3$ . These results, however, are obtained at temperatures lower than 590 K, while the rate order Nam *et al.* (26) proposed (first order in both NO and  $\text{NH}_3$ ) fits the experimental results in the range 475–775 K. Further, it has been reported that in

the presence of O<sub>2</sub> there is a change in the selectivity for the NO + NH<sub>3</sub> + O<sub>2</sub> reaction above 525 K (23).

Our results on V<sub>2</sub>O<sub>5</sub> indicate that NO can interact at low temperatures with a reduced vanadia surface but that it cannot be adsorbed on an oxidized surface (Fig. 6). To comply with the kinetic results described in the literature, one needs to assume NO adsorption on the support. On anatase at least two different NO species can adsorb. The first is weakly bound to the titania surface (Fig. 8); the second remains adsorbed even at 775 K and poisons the titania surface preventing further adsorption of NO molecules. When the NO pressure increases the adsorption energy of the weakly bound NO species increases and the maximum in the TDS spectra shifts from 385 to 468 K; there is then a possible source of NO molecules for the reduced vanadium sites at the TiO<sub>2</sub> surface. Also, a positive dependence on the amount adsorbed with pressure is observed fitting the positive order in NO observed in kinetic experiments.

The elementary steps, Eqs. (1) to (7), described above cannot explain the presence of ammonia adsorbed on the vanadium catalyst in the high temperature range; in addition these ammonia species are unreactive toward NO. This strongly adsorbed species might be understood as NH<sub>3</sub> molecules that dissociate on the surface of the reduced V<sub>2</sub>O<sub>5</sub> sample according to



Existence of this VNH<sub>2</sub> species finds support in XPS and ESR data (38). Moreover, Otto *et al.* (14, 47) claim that the primary step in the NH<sub>3</sub> + NO reaction is the formation of NH<sub>2</sub> species. In addition to this, spectroscopic evidence for the formation of NH<sub>x</sub> species has also been extensively reported (48–50).

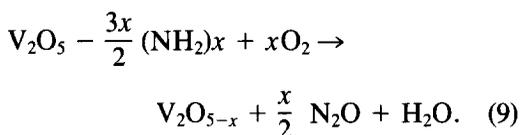
Janssen *et al.* (27) proposed the heterolytic dissociation of NH<sub>3</sub> over two adjacent

VO groups, which after reaction with adsorbed NO is the source of N<sub>2</sub> in the products' mainstream. This proposal is in agreement with the observation of Faber and Harris (42) of the formation of NH<sub>2</sub>NO. However, the fact that NH<sub>3</sub> can adsorb on a reduced vanadia surface, leading to an apparent oxidation of vanadium species as observed by XPS (38) and the presence of ESR signals corresponding to electrons trapped in oxygen vacancies after NH<sub>3</sub> treatments (38), supports the idea of a dissociative homolytic adsorption on the reduced surface activated at the reaction temperatures.

Table 1 shows that ammonia does not adsorb or does so very weakly on fully hydroxylated vanadia surfaces. In the absence of O<sub>2</sub> the removal of the adsorbed water is needed to reach a steady-state reaction (18, 28). If molecular oxygen is present, the oxidation of the hydroxylated reduced sites is easier than in the absence of O<sub>2</sub> according to Wehrli and Stumm (46).

At temperatures below 525 K, provided NH<sub>3</sub> has reduced the vanadia surface and water has been formed, ammonia and nitric oxide can compete for the reduced surface sites, which in the absence of O<sub>2</sub> leads to a decrease in the rate of NO reduction. This explains the generally agreed on effect of O<sub>2</sub> on the rate of NO reduction (1, 23, 25, 45), namely, a sharp increase in the NO conversion in the presence of O<sub>2</sub>.

O<sub>2</sub> treatment at 675 K restores the original V<sub>2</sub>O<sub>5</sub> surface, suggesting the oxidation of such VNH<sub>2</sub> species in the presence of O<sub>2</sub>. The stoichiometric step should be described by



By combining the elementary steps described by Eqs. (5) and (7) to (9), the side reaction that leads to the increase in N<sub>2</sub>O

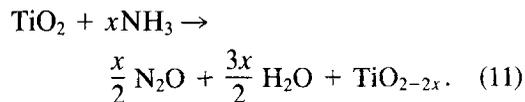
concentration as the reaction temperature increases is obtained:



Over  $\text{V}_2\text{O}_5$ , the evolution of  $\text{N}_2\text{O}$  at temperatures above 675 K in the oxidation of  $\text{NH}_3$  has been reported (51). This side reaction may explain the change in selectivity for the NO reduction at temperatures above 525 K (23). If a competitive adsorption takes place, the number of sites available for the reduction of NO may decrease, leading to a drop in NO conversion; additionally, in the presence of  $\text{O}_2$  the  $\text{VNH}_2$  species are oxidized to  $\text{V}^{5+}$  and  $\text{N}_2\text{O}$ , increasing the  $\text{N}_2\text{O}$  concentration in the reaction products.

On the basis of the large number of observations reported, the two simultaneous reaction mechanisms proposed by Nam *et al.* (26) seem to agree with our results.

However, for the case of supported  $\text{V}_2\text{O}_5$  other pathways for the production of  $\text{N}_2\text{O}$  may be considered, particularly the report that  $\text{TiO}_2$  is able to produce  $\text{N}_2\text{O}$  (25). But, as shown earlier,  $\text{N}_2$  or  $\text{N}_2\text{O}$  is not produced by the reaction of NO and  $\text{NH}_3$  on the  $\text{TiO}_2$  surface. Thus, the reported production of  $\text{N}_2\text{O}$  in the NO +  $\text{NH}_3$  reaction over  $\text{TiO}_2$  samples (25) could be associated with the reduction of the  $\text{TiO}_2$  surface by  $\text{NH}_3$  at high temperatures, leading to the formation of  $\text{N}_2\text{O}$  which is thermodynamically stable at temperatures of ca. 675 K. In fact, Busca *et al.* have reported the presence of  $\text{NH}_3$  species held by  $\text{TiO}_2$  at temperatures higher than 750 K, and the presence of  $\text{Ti}^{3+}$  ions on vanadia/titania catalysts after reduction (52) gives support to the following step:



Interaction of two NO molecules at the titania surface should be dismissed as a source of  $\text{N}_2$  or  $\text{N}_2\text{O}$  since it has not been possible to detect either species by TDS or TPRS.

## SUMMARY AND CONCLUSIONS

The adsorption of  $\text{NH}_3$  and NO on pure vanadia and on  $\text{TiO}_2$  under pressures (up to 25 Torr) and at near-industrial temperatures (room temperature to 675 K) has been studied by AES and TDS, using a UHV chamber equipped with a built-in high pressure cell (up to 1 atm).

$\text{NH}_3$  adsorption takes place over the whole range of temperatures studied on both  $\text{V}_2\text{O}_5$  and reduced  $\text{V}_2\text{O}_5$  surfaces while NO adsorption occurs only on reduced  $\text{V}_2\text{O}_5$  surfaces.  $\text{TiO}_2$  adsorbs  $\text{NH}_3$  as well as NO.

The  $\text{V}_2\text{O}_5/\text{TiO}_2$  catalyst currently employed for reducing  $\text{NO}_x$  emissions from power plants can be understood as a bifunctional catalyst. Extrapolating from the data with pure  $\text{V}_2\text{O}_5$  and pure  $\text{TiO}_2$  to  $\text{V}_2\text{O}_5/\text{TiO}_2$  catalysts, one can propose that the adsorption of ammonia takes place mainly on the vanadium component causing the reduction of the original  $\text{V}^{5+}$  species. In turn the NO adsorption takes place on the  $\text{TiO}_2$  support, since oxidized vanadia samples are completely unable to adsorb NO. The reduction of NO to  $\text{N}_2$  would occur through a Langmuir-Hinshelwood mechanism or a spillover onto the surface of the vanadia component that implies the migration of the adsorbed NO species from the support to the reduced vanadium sites. In the absence of  $\text{O}_2$ , however, the catalyst loses activity since the reduced vanadium species can interact with ammonia molecules in the gas phase, leading to the formation of  $\text{VNH}_x$  species which are completely unreactive towards NO.

Furthermore, oxidation of the  $\text{NH}_3$  to  $\text{N}_2\text{O}$  has been demonstrated by TDS on oxidized vanadium species. It has also been shown that reduced vanadia can be oxidized by reduction of  $\text{N}_2\text{O}$  to  $\text{N}_2$ . Since  $\text{TiO}_2$  was not able to generate  $\text{N}_2\text{O}$  after heating in NO at reaction temperatures, a similar redox cycle on the surface of the support involving ammonia is proposed. This also leads to the formation of  $\text{NH}_x$  spe-

cies on the surface of the catalyst that, in the presence of O<sub>2</sub>, leads to the formation of N<sub>2</sub>O, as has been reported in the literature. This process also explains the decrease in the catalytic activity as a function of the temperature because of the poisoning of active surface sites.

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